

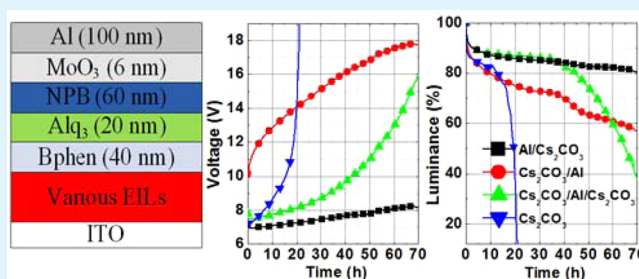
# Highly Efficient and Stable Electron Injection Layer for Inverted Organic Light-Emitting Diodes

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**ABSTRACT:** A highly efficient and stable electron injection layer (EIL) for inverted organic light-emitting diodes (OLEDs) is developed. A 1 nm-thick Al is deposited between indium tin oxide cathode and commonly used Cs<sub>2</sub>CO<sub>3</sub> EIL, which can significantly improve the stability. The Al may react with evaporated Cs<sub>2</sub>CO<sub>3</sub> and form a much stabler Al–O–Cs complex, avoiding Cs oxidization by air according to X-ray photoemission spectroscopy measurement. When the Al is evaporated after Cs<sub>2</sub>CO<sub>3</sub> layer, although such a Al–O–Cs complex also forms, the inferior electron injection at Al/4,7-diphenyl-1,10-phenanthroline interface leads to a joule heat-induced resistance that adversely affects the air stability of the device. It is expected that the developed Al/Cs<sub>2</sub>CO<sub>3</sub> EIL promotes high efficiency and stable active-matrix OLEDs based on n-type thin film transistor.

**KEYWORDS:** high efficiency, air stability, electron injection layer, inverted OLED



## INTRODUCTION

Active matrix organic light-emitting diode (AMOLED)<sup>1,2</sup> has been commercialized in smart phones and TVs produced by Samsung and LG. Currently, the backplane of AMOLED is fabricated on the basis of a low temperature poly silicon-thin film transistor (LTPS-TFT) array, due to the high mobility and stability of LTPS.<sup>3,4</sup> However, LTPS fabrication requires an excimer-laser annealing (ELA) process, which results in nonuniformity and deteriorates production yield, especially for large size panels. On the other hand, indium gallium zinc oxide (IGZO)-TFT for AMOLED is an attractive alternative because it provides unique advantages of uniformity, large area, and low cost.<sup>5,6</sup> The n-type nature of IGZO promotes integration of IGZO-TFT and inverted OLED with a bottom cathode, to maintain the stability of OLED driven by the voltage controlled current source.<sup>7–9</sup> Because of the high optical transparency and electrical conductivity, indium tin oxide (ITO) is widely used as a cathode of inverted OLED. However, its high work function limits electron injection into the neighboring electron-transporting layer (ETL). Bulk n-type doped ETL by alkali metals or their compounds<sup>10–12</sup> (e.g., Li, Cs, Rb<sub>2</sub>CO<sub>3</sub>, Cs<sub>2</sub>CO<sub>3</sub>) are usually sandwiched between ITO and undoped ETL to facilitate electron injection from ITO. To simplify the fabrication, on the other hand, an ultrathin interlayer<sup>13–15</sup> such as LiF, Liq, and Cs<sub>2</sub>CO<sub>3</sub> is often used as the electron-injecting layer (EIL). Such EILs have been proved to possess excellent electron injecting property, but they readily decompose to alkali metals that are prone to be oxidized in air, leading to long-term instability. Recently, solution processed conjugated polyelectrolytes<sup>16</sup> or n-type metal oxides such as zinc oxide (ZnO),<sup>17</sup> titanium dioxide (TiO<sub>2</sub>),<sup>18</sup> tin dioxide

(SnO<sub>2</sub>),<sup>19</sup> and zirconium dioxide (ZrO<sub>2</sub>)<sup>20</sup> have been developed as promising candidates for air-stable EIL. However, these metal oxides fabricated by the sol-gel method require a high annealing temperature over 300 °C for better electron injecting ability, and complete coverage of metal oxide with large surface roughness needs enough thick ETL, which will lead to high operating voltages. Although metal oxide can be deposited by sputtering at relatively low temperature, using sputtered metal oxide as EILs in organic optoelectronic devices such as OLED and organic photovoltaic cell (OPV) is rarely reported. Thermal evaporation of alkali metal compound such as Cs<sub>2</sub>CO<sub>3</sub> powder is simple and easily controlled, and the subsequent deposition of organic layers is continuously accomplished in one chamber. On the contrary, sputtering metal oxide requires additional equipment and complex processes. Besides, the cost of Cs<sub>2</sub>CO<sub>3</sub> powder is significantly lower than that of the metal oxide target. Therefore, thermal evaporation of alkali metal compound as EIL is more preferable in the OLED field, especially for research. For inverted OLED, it is still important and urgent to develop stable and easily fabricated EIL.

Here, the widely used EIL Cs<sub>2</sub>CO<sub>3</sub> is modified to develop highly efficient and stable EIL for inverted device. Unlike the commonly used EIL LiF or Liq that requires the reaction with Al to liberate Li atoms, the thermal evaporated Cs<sub>2</sub>CO<sub>3</sub> does not need an external metal layer to produce Cs, because decomposition of evaporated Cs<sub>2</sub>CO<sub>3</sub> to Cs is thermodynamically

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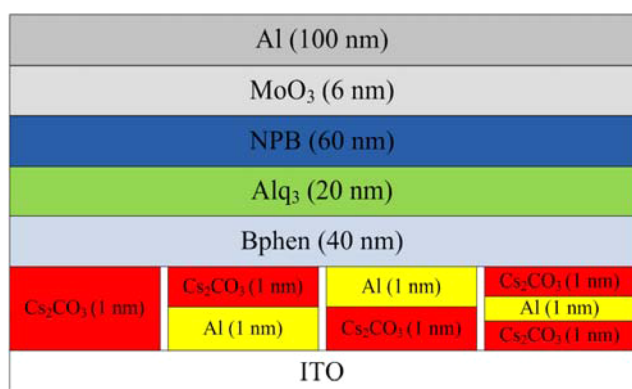
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cally allowed.<sup>21</sup> However, by depositing an ultrathin Al between ITO and Cs<sub>2</sub>CO<sub>3</sub>, the instability of the evaporated Cs<sub>2</sub>CO<sub>3</sub> layer because of easy oxidation of Cs is significantly improved. To investigate the functionality of the thin Al layer, it is inserted at various positions in the device and analyzed by their surface electronic properties and work functions.

## EXPERIMENTAL SECTION

The inverted devices were fabricated on ITO-coated glass substrates. Prior to film deposition, the ITO glass substrates were cleaned successively using deionized water, acetone, and isopropanol under an ultrasonic bath, and then treated with UV-ozone after drying. The devices with four kinds of EILs, Cs<sub>2</sub>CO<sub>3</sub> (1 nm), Al (1 nm)/Cs<sub>2</sub>CO<sub>3</sub> (1 nm), Cs<sub>2</sub>CO<sub>3</sub> (1 nm)/Al (1 nm), and Cs<sub>2</sub>CO<sub>3</sub> (1 nm)/Al (1 nm)/Cs<sub>2</sub>CO<sub>3</sub> (1 nm), were fabricated. For fabrication of Al/Cs<sub>2</sub>CO<sub>3</sub> and Cs<sub>2</sub>CO<sub>3</sub>/Al on ITO, Al and Cs<sub>2</sub>CO<sub>3</sub> were first deposited on ITO, respectively. As shown in Figure 1, the structure of the device is ITO/



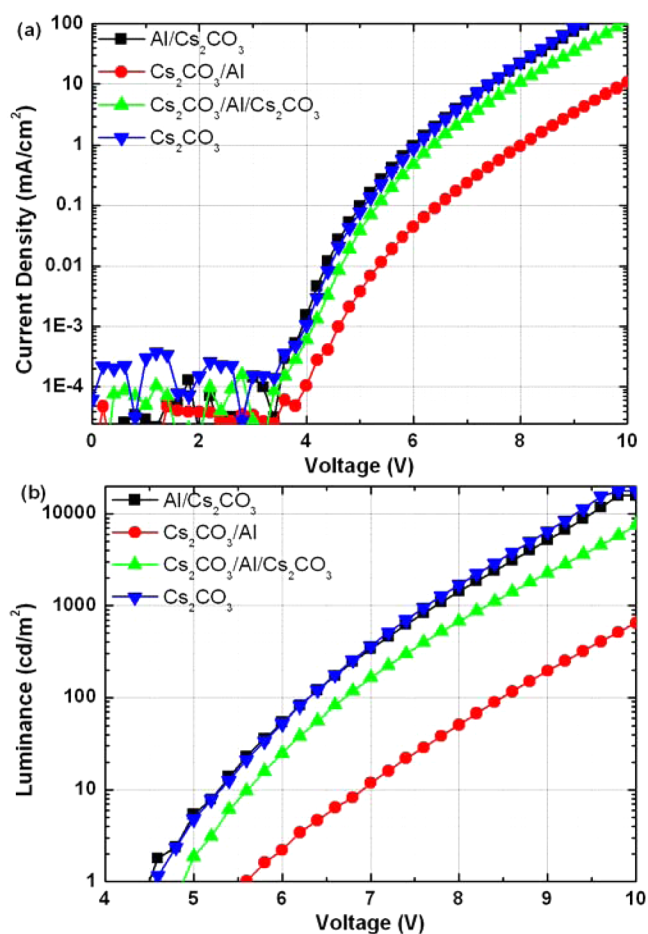
**Figure 1.** Device structures of inverted OLEDs with various EILs: Cs<sub>2</sub>CO<sub>3</sub> (1 nm), Al (1 nm)/Cs<sub>2</sub>CO<sub>3</sub> (1 nm), Cs<sub>2</sub>CO<sub>3</sub> (1 nm)/Al (1 nm), and Cs<sub>2</sub>CO<sub>3</sub> (1 nm)/Al (1 nm)/Cs<sub>2</sub>CO<sub>3</sub> (1 nm).

EIL/ETL (40 nm)/emission layer (EML) (20 nm)/hole transporting layer (HTL) (60 nm)/hole injection layer (HIL) (6 nm)/Al (100 nm), where ETL, EML, HTL, and HIL are BPhen, Alq<sub>3</sub>, *N,N*-di(1-naphthyl)-*N,N*-diphenyl-(1,1'-biphenyl)-4,4'-diamine (NPB), and MoO<sub>3</sub>, respectively.

The EIL, ETL, EML, HTL, HIL, and anode Al were thermally deposited in a high vacuum deposition system at a base pressure of 10<sup>-6</sup> Torr. The deposition rate for organic materials was detected by quartz-crystal monitors within the range from 0.01 to 0.1 nm/s. The devices' current density–voltage (*J*–*V*) and luminance–voltage (*L*–*V*) characteristics were measured with a computer controlled Keithley 2400 source meter and BM-7A luminance colorimeter immediately after finishing fabrication without encapsulation under ambient conditions. Because we can get four identical devices on one substrate, the remaining untested devices were used to test their voltage rise and luminance decay. The devices for stability test were operated at a fixed current density of 10 mA/cm<sup>2</sup>. X-ray and ultraviolet photoemission spectroscopy (XPS and UPS) measurements were carried out in a Kratos AXIS UltraDLD ultrahigh vacuum surface analysis system with a monochromatic aluminum *K*α source (1486.6 eV) and a He I (21.2 eV) gas discharge lamp, respectively.

## RESULTS AND DISCUSSION

Cs<sub>2</sub>CO<sub>3</sub> has been widely used to facilitate electron injection from ITO to ETL in inverted OLED. However, whether ITO/Cs<sub>2</sub>CO<sub>3</sub> interface or Cs<sub>2</sub>CO<sub>3</sub>/ETL interface dominates the electron injection requires further study. To address this question, an ultrathin Al layer was deposited before or after Cs<sub>2</sub>CO<sub>3</sub> layer to investigate the effects of Al on electron injection from ITO to ETL. As shown in Figure 2, all devices

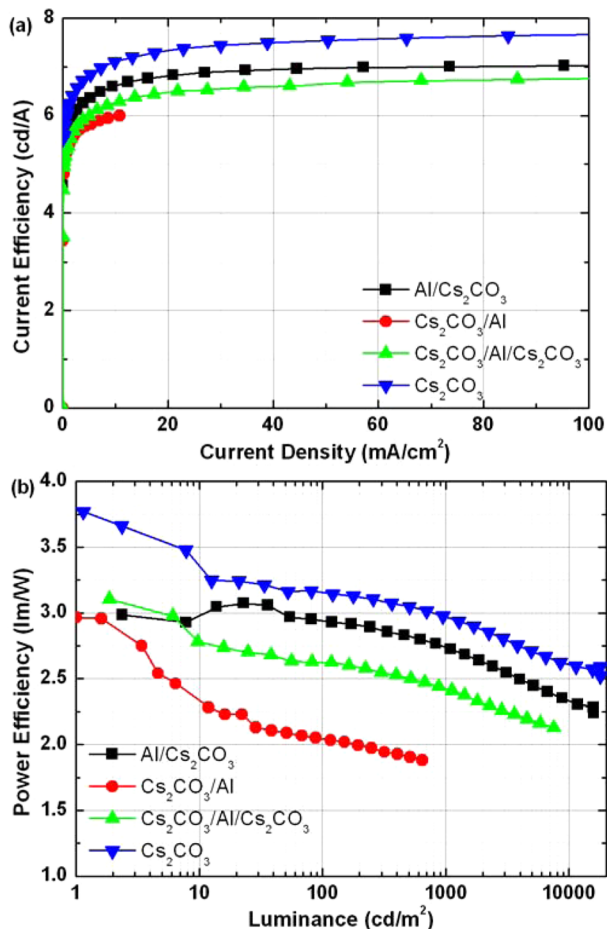


**Figure 2.** Current density–voltage (a) and luminance–voltage (b) characteristics of inverted devices with various EILs.

with Cs<sub>2</sub>CO<sub>3</sub> EIL directly contacting BPhen layer behave very similarly, whereas their current densities and luminance are significantly larger than those of the device with Al inserted between Cs<sub>2</sub>CO<sub>3</sub> and BPhen layer. For example, at a current density of 10 mA/cm<sup>2</sup>, the driving voltage of the Cs<sub>2</sub>CO<sub>3</sub>-based device is about 7.2 V, while that of the Cs<sub>2</sub>CO<sub>3</sub>/Al-based device is about 10 V. The turn-on voltage (*V*<sub>on</sub>) for 1 cd/m<sup>2</sup> of the Cs<sub>2</sub>CO<sub>3</sub>-based device is 4.5 V, while that of the Cs<sub>2</sub>CO<sub>3</sub>/Al-based device is 5.5 V. This indicates that the Cs<sub>2</sub>CO<sub>3</sub>/BPhen interface has superior electron injection property than (Cs<sub>2</sub>CO<sub>3</sub>/Al)/BPhen interface. The favorable electron injection by Cs<sub>2</sub>CO<sub>3</sub>/BPhen interface is attributed to the n-type doped BPhen by Cs<sub>2</sub>CO<sub>3</sub> at the interface. The electron transfer from Cs<sub>2</sub>CO<sub>3</sub> to BPhen leads to a shift of Fermi level to the lowest unoccupied molecular orbital (LUMO) of BPhen.<sup>22</sup> The subsequent deposition of Al on top of Cs<sub>2</sub>CO<sub>3</sub> impedes charge transfer at the Cs<sub>2</sub>CO<sub>3</sub>/BPhen interface, resulting in inferior electron injection for the device with Cs<sub>2</sub>CO<sub>3</sub>/Al EIL. For the device with Al/Cs<sub>2</sub>CO<sub>3</sub> EIL, it exhibits *J*–*V* and *L*–*V* characteristics almost identical to those of the device without Al, indicating a negligible effect of ultrathin layer Al between ITO and Cs<sub>2</sub>CO<sub>3</sub> on electron injection. This further demonstrates that Cs<sub>2</sub>CO<sub>3</sub>/ETL interface instead of ITO/Cs<sub>2</sub>CO<sub>3</sub> interface dominates electron injection for the inverted device. The deteriorated electron injection property for Cs<sub>2</sub>CO<sub>3</sub>/Al can be healed by adding another Cs<sub>2</sub>CO<sub>3</sub> layer on top of Cs<sub>2</sub>CO<sub>3</sub>/Al bilayer. As compared to the device with

$\text{Cs}_2\text{CO}_3/\text{Al}$ , the device with  $\text{Cs}_2\text{CO}_3/\text{Al}/\text{Cs}_2\text{CO}_3$  displays dramatically increased current density and reduced turn-on voltage, which approaches  $J$ - $V$  and  $L$ - $V$  characteristics of the device with EIL  $\text{Cs}_2\text{CO}_3$  or  $\text{Al}/\text{Cs}_2\text{CO}_3$ .

Figure 3 compares the CE and power efficiency (PE) of inverted devices with various EILs. At the same current density,

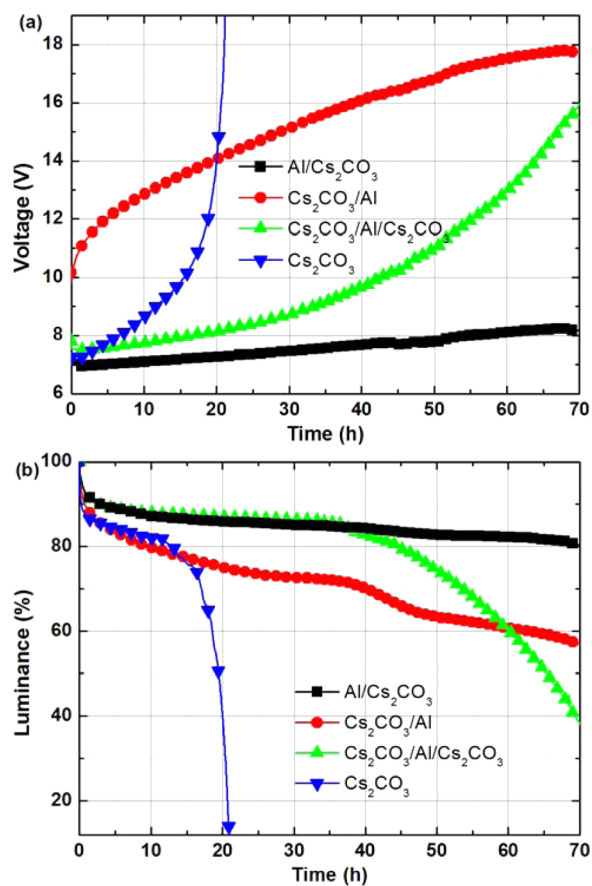


**Figure 3.** Current efficiency–current density (a) and power efficiency–luminance (b) characteristics of inverted devices with various EILs.

the device with  $\text{Cs}_2\text{CO}_3/\text{Al}$  EIL shows the lowest CE and PE. Because of the superior hole injection ability of  $\text{MoO}_3$  top-contact and the inferior electron injection ability of  $\text{Cs}_2\text{CO}_3/\text{Al}$ , a larger amount of holes than electrons are transported into the  $\text{Alq}_3$  emitter, and excess holes produce unstable  $\text{Alq}^{3+}$  cations that lead to excitons quenching. This is responsible for low CE for device with  $\text{Cs}_2\text{CO}_3/\text{Al}$  as EIL, and also its inferior electron injection determines the low PE of device with high driving voltage. As electron injection ability of EIL increases, recombination of holes and electrons is balanced and the formation of unstable  $\text{Alq}^{3+}$  cations is suppressed, resulting in enhanced CE of the device. The device with  $\text{Al}/\text{Cs}_2\text{CO}_3$  EIL achieves an increased CE of about 7.0 cd/A, and that with  $\text{Cs}_2\text{CO}_3$  EIL has the largest CE of about 7.5 cd/A. To the best of our knowledge, such CE values are among the highest values ever reported for a  $\text{Alq}_3$ -based device. Moreover, the current efficiencies of all inverted devices grow with current density until they tend to saturation at a current density larger than 20  $\text{mA}/\text{cm}^2$ . Because the hole injection ability of  $\text{MoO}_3$  top-contact is larger than the electron injection ability of bottom-

contact  $\text{Cs}_2\text{CO}_3$ , holes are favorably injected and accumulated at the  $\text{BPhen}/\text{Alq}_3$  interface, resulting in recombination location at the  $\text{BPhen}/\text{Alq}_3$  interface at low driving voltage. As the driving voltage increased, electron injection from ITO is enhanced. This leads to the extended recombination zone into the  $\text{Alq}_3$  bulk layer, resulting in higher CE at higher driving voltage. As shown in Figure 3, the PE of the proposed EIL  $\text{Al}/\text{Cs}_2\text{CO}_3$ -based device is slightly lower than that of the  $\text{Cs}_2\text{CO}_3$ -based device, which is not attributed to poorer electron injection property of  $\text{Al}/\text{Cs}_2\text{CO}_3$ . Actually, even slightly higher current is observed with  $\text{Al}/\text{Cs}_2\text{CO}_3$  EIL in Figure 2. The slightly lower PE may be due to the change of charge carrier balance. On the other hand, such a small difference (<10%) could also result from process or measurement variation.

Besides the electron injection property of EIL, its long-term stability is also an important issue. We have evaluated the voltage rise and luminance decay of inverted devices with various EILs at a fixed current density of 10  $\text{mA}/\text{cm}^2$ . All of the devices were exposed in ambient condition without encapsulation. The inverted device without encapsulation is to accelerate the degradation process to compare the stability of  $\text{Al}/\text{Cs}_2\text{CO}_3$  and  $\text{Cs}_2\text{CO}_3$  EIL. Although encapsulation can protect the device from being oxidized, the water and oxygen still penetrate into the device even with the encapsulation technique state of the art, especially with the thin film encapsulation for flexible device. As shown in Figure 4, during a 21 h operation test, the device with  $\text{Cs}_2\text{CO}_3$  EIL shows significantly increased driving voltage by 12 V, and its

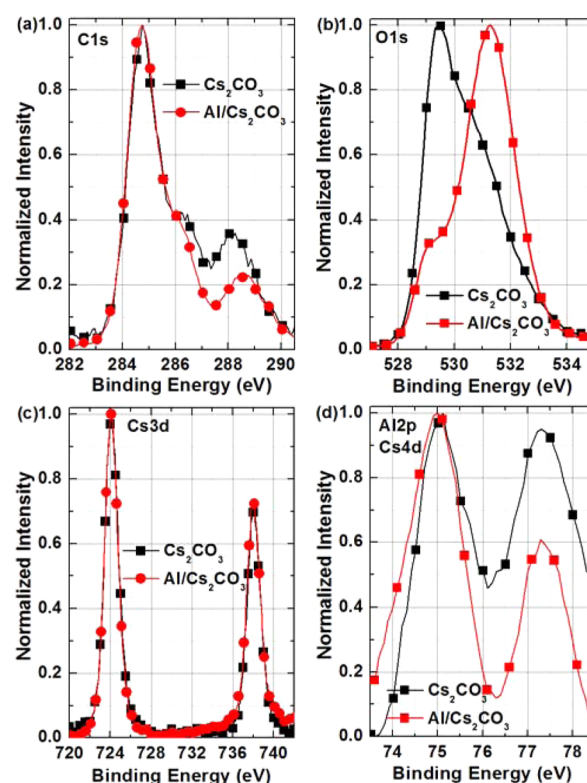


**Figure 4.** Voltage rise (a) and luminance decay (b) of inverted devices with various EILs.



luminance seriously drops to 10% of the initial value. This indicates that the electron injection barrier between ITO and the thermal evaporated  $\text{Cs}_2\text{CO}_3$  layer gradually increases with time. The thermal evaporated  $\text{Cs}_2\text{CO}_3$  was reported to decompose metallic Cs rather than into  $\text{Cs}_2\text{O}$ . The low work function of Cs with 1.9 eV renders it easily oxidized by water and oxygen. If the evaporated  $\text{Cs}_2\text{CO}_3$  on the ITO substrate is pristine or decomposes to  $\text{Cs}_2\text{O}$ , the inverted device should not have a badly deteriorated performance, as  $\text{Cs}_2\text{CO}_3$  or  $\text{Cs}_2\text{O}$  is hardly oxidized by oxygen.<sup>23</sup> Therefore, the oxidation of Cs in air contributes to the instability of thermal evaporated  $\text{Cs}_2\text{CO}_3$ . However, the ultrathin Al layer deposited between ITO and  $\text{Cs}_2\text{CO}_3$  may prevent oxidation of Cs. Although Al/ $\text{Cs}_2\text{CO}_3$  and  $\text{Cs}_2\text{CO}_3$  possess almost identical electron injection properties, the stability of Al/ $\text{Cs}_2\text{CO}_3$  is significantly superior to that of  $\text{Cs}_2\text{CO}_3$ . During 70 h operation test, the driving voltage rise of device with EIL Al/ $\text{Cs}_2\text{CO}_3$  is just about 1 V, and the luminance of that decays to 80% of its initial value. The high stability of the Al/ $\text{Cs}_2\text{CO}_3$ -based device should be originated from the Al–O–Cs complex<sup>24</sup> produced by chemical reaction of subsequent evaporated  $\text{Cs}_2\text{CO}_3$  and underlying Al. As compared to the metallic Cs, the Al–O–Cs complex is less prone to be oxidized by oxygen. For  $\text{Cs}_2\text{CO}_3$ /Al EIL, the evaporation of Al on top of  $\text{Cs}_2\text{CO}_3$  can also lead to the Al–O–Cs complex, leading to better stability of  $\text{Cs}_2\text{CO}_3$ /Al EIL than that of  $\text{Cs}_2\text{CO}_3$  EIL. However, the device with  $\text{Cs}_2\text{CO}_3$ /Al EIL exhibits larger voltage rise, as compared to that with Al/ $\text{Cs}_2\text{CO}_3$  EIL. This is related to distinctly different electron injection properties of  $\text{Cs}_2\text{CO}_3$ /Al and Al/ $\text{Cs}_2\text{CO}_3$  as shown in Figure 2. Because of the weak electron injection capability of  $\text{Cs}_2\text{CO}_3$ /Al, a large amount of electrons accumulates at the ( $\text{Cs}_2\text{CO}_3$ /Al)/BPhen interface, leading to excess joule heat at such interface. This will damage the adjacent organic layer BPhen with low glass transition temperature, resulting in increased resistance and large voltage rise of the device. Conversely, the joule heat-induced resistance is suppressed in the Al/ $\text{Cs}_2\text{CO}_3$ -based device with excellent electron injection property. Because the Al–O–Cs complex forms in both EILs, the question that why devices with EIL  $\text{Cs}_2\text{CO}_3$ /Al and Al/ $\text{Cs}_2\text{CO}_3$  exhibit distinctly different characteristics as shown in Figure 2 is raised. We present the reason as follows. The cover of Al on  $\text{Cs}_2\text{CO}_3$  or  $\text{Cs}_2\text{CO}_3$  on Al does not completely convert to Al–O–Cs complex, leaving original Al or  $\text{Cs}_2\text{CO}_3$  to form Al/BPhen or  $\text{Cs}_2\text{CO}_3$ /BPhen interface. The deposition of another  $\text{Cs}_2\text{CO}_3$  on top of  $\text{Cs}_2\text{CO}_3$ /Al produces a new  $\text{Cs}_2\text{CO}_3$ /BPhen interface, but the second evaporated  $\text{Cs}_2\text{CO}_3$  layer mainly stays pristine because most of the Al has reacted with the underlying evaporated  $\text{Cs}_2\text{CO}_3$ . This contributes to high voltage rise for the device with EIL  $\text{Cs}_2\text{CO}_3$ /Al/ $\text{Cs}_2\text{CO}_3$ .

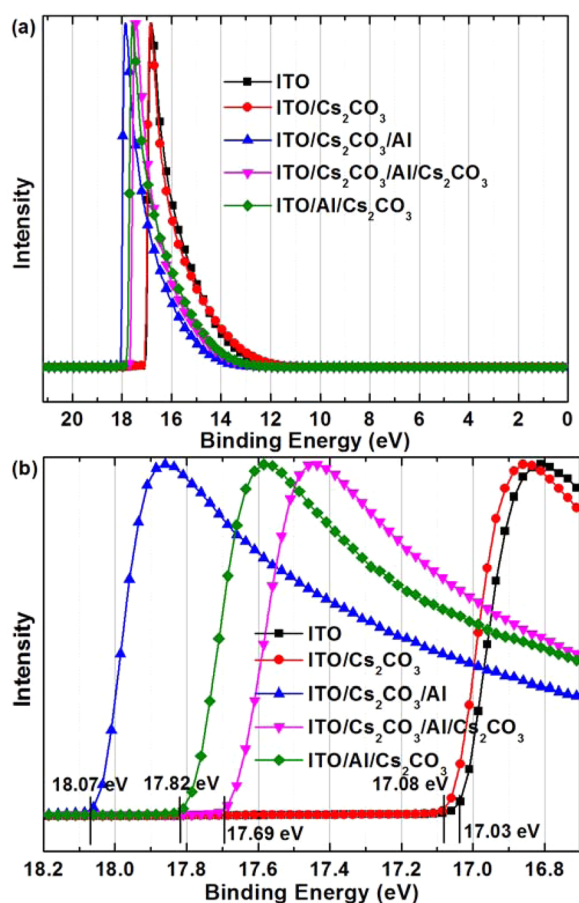
To further understand the mechanism for the higher stability of Al/ $\text{Cs}_2\text{CO}_3$  than  $\text{Cs}_2\text{CO}_3$ , the evaporated Al/ $\text{Cs}_2\text{CO}_3$  and  $\text{Cs}_2\text{CO}_3$  films on top of ITO have been studied by XPS, as shown in Figure 5. The films were exposed in air for about 10 min prior to the measurements. Because of the highly reactive and catalytic Cs from evaporated  $\text{Cs}_2\text{CO}_3$ , oxygenated chemicals such as  $\text{H}_2\text{O}$ ,  $\text{CO}_2$ , and  $\text{O}_2$  in air can easily adsorb on Cs to induce a complicated hydroxylation and carbonylation reaction,<sup>25</sup> which correspond to the C 1s peaks at 286.1 and 288.1 eV for evaporated  $\text{Cs}_2\text{CO}_3$  film, respectively. That is why evaporated  $\text{Cs}_2\text{CO}_3$  exhibits deteriorated electron injection stability in air. However, the intensities of C 1s peaks at 286.1 and 288.1 eV for Al/ $\text{Cs}_2\text{CO}_3$  are reduced, referring that the



**Figure 5.** C 1s (a), O 1s (b), Cs 3d (c), and Al 2p and Cs 4d (d) spectra of  $\text{Cs}_2\text{CO}_3$  and Al/ $\text{Cs}_2\text{CO}_3$  films exposed in air for about 10 min.

induced chemical reaction on Cs is suppressed by Al. The reaction of Al with the subsequent evaporated  $\text{Cs}_2\text{CO}_3$  should prevent further catalysis reaction on the latter. As shown in Figure 5d, the Al 2p band and the Cs 4d band are overlapped, and the binding energy at 74 eV indicates oxidized Al. Moreover, as compared to those for pristine Cs,<sup>22</sup> the Cs 3d peaks for Al/ $\text{Cs}_2\text{CO}_3$  are shifted to lower binding energies at 724.1 and 738.1 eV, indicating oxidized Cs in Al/ $\text{Cs}_2\text{CO}_3$  film. Therefore, the product for Al/ $\text{Cs}_2\text{CO}_3$  is speculated to be Al–O–Cs complex<sup>24</sup> that also possesses excellent electron injection property. Although both Cs 3d peaks for Al/ $\text{Cs}_2\text{CO}_3$  and  $\text{Cs}_2\text{CO}_3$  are almost identical, the products of oxidation of Cs for Al/ $\text{Cs}_2\text{CO}_3$  and  $\text{Cs}_2\text{CO}_3$  films are different. For O 1s spectra, they show two characteristic peaks, which should be assigned to the ITO at 529.3 eV and oxidized Cs or Al at 531.3 eV, respectively. The dominated O 1s peak at 531.3 eV for Al/ $\text{Cs}_2\text{CO}_3$  indicates that the Al–O–Cs complex is formed on ITO. Because of the reduced catalysis and reactivity of the Al–O–Cs complex, it is hard to further oxidize. As a result, the Al/ $\text{Cs}_2\text{CO}_3$  film shows efficient and stable electron injection ability.

UPS has been used to measure the work functions of bare ITO and ITO modified by  $\text{Cs}_2\text{CO}_3$ ,  $\text{Cs}_2\text{CO}_3$ /Al,  $\text{Cs}_2\text{CO}_3$ /Al/ $\text{Cs}_2\text{CO}_3$ , and Al/ $\text{Cs}_2\text{CO}_3$ . Because of unavoidable air exposure of samples loaded into test equipment in our lab, the measured work functions are not for the pristine EILs, but reflect the air stability of EILs. As shown in Figure 6b, the photoemission onsets of ITO, ITO/ $\text{Cs}_2\text{CO}_3$ , ITO/ $\text{Cs}_2\text{CO}_3$ /Al, ITO/ $\text{Cs}_2\text{CO}_3$ /Al/ $\text{Cs}_2\text{CO}_3$ , and ITO/Al/ $\text{Cs}_2\text{CO}_3$  are found at 17.03, 17.08, 18.07, 17.69, and 17.82, which correspond to the work functions of 4.17, 4.12, 3.13, 3.51, and 3.38 eV, respectively. The evaporated  $\text{Cs}_2\text{CO}_3$  has been proved to be an efficient EIL,



**Figure 6.** UPS spectra of air-exposed ITO and ITO modified by different EILs: (a) the full UPS spectrum using He I radiation, and (b) secondary-electron cutoff.

and the work function of ITO/ $\text{Cs}_2\text{CO}_3$  was about  $0.4 \text{ eV}^{26}$  or even  $1.0 \text{ eV}^{15}$  lower than that of ITO in previous reports. However, an almost identical work function in our measurement indicates the invalid electron injection of  $\text{Cs}_2\text{CO}_3$  by air exposure, and further proves that the evaporated  $\text{Cs}_2\text{CO}_3$  is unstable. The 1 nm Al deposition on or beneath  $\text{Cs}_2\text{CO}_3$  can produce Al–O–Cs complex, providing enhanced air stability, and their work functions remain lower than that of ITO even exposed to air. However, their electron injection properties are quite different. The current density of the ITO/ $\text{Cs}_2\text{CO}_3$ /Al-based device is much lower than that of the ITO/Al/ $\text{Cs}_2\text{CO}_3$ -based device, although ITO/ $\text{Cs}_2\text{CO}_3$ /Al has a lower work function, indicating that the n-type doped  $\text{Cs}_2\text{CO}_3$ /BPhen interface instead of work function of EIL-modified ITO dominates electron injection from ITO to BPhen. When depositing another thin layer of  $\text{Cs}_2\text{CO}_3$  on top of ITO/ $\text{Cs}_2\text{CO}_3$ /Al, the current density is greatly enhanced, although the work function is higher, which further confirms the importance of the  $\text{Cs}_2\text{CO}_3$ /BPhen interface for electron injection. Comparing Al/ $\text{Cs}_2\text{CO}_3$  and  $\text{Cs}_2\text{CO}_3$ /Al/ $\text{Cs}_2\text{CO}_3$ , because both devices have the n-type doping at the  $\text{Cs}_2\text{CO}_3$ /BPhen interface, the higher current density of the Al/ $\text{Cs}_2\text{CO}_3$ -based device is mainly originated from the lower work function of ITO/Al/ $\text{Cs}_2\text{CO}_3$  than that of ITO/ $\text{Cs}_2\text{CO}_3$ /Al/ $\text{Cs}_2\text{CO}_3$ .

## CONCLUSION

In summary, we have developed a highly efficient and stable Al/ $\text{Cs}_2\text{CO}_3$  EIL for inverted OLEDs. The device with such EIL

shows almost identical  $J$ – $V$  and  $L$ – $V$  characteristics with the common  $\text{Cs}_2\text{CO}_3$ -only EIL device, due to the favorable electron injection for the same  $\text{Cs}_2\text{CO}_3$ /BPhen interfaces. The inverted devices using Alq<sub>3</sub> as EML achieve current efficiencies of 7.0 and 7.5 cd/A when Al/ $\text{Cs}_2\text{CO}_3$  and  $\text{Cs}_2\text{CO}_3$  are employed as EIL, respectively. To the best of our knowledge, such efficiencies are among the highest values ever reported for an Alq<sub>3</sub>-based device. However, due to the fast oxidation of Cs decomposed from the evaporated  $\text{Cs}_2\text{CO}_3$ ,  $\text{Cs}_2\text{CO}_3$ -based device without encapsulation shows seriously deteriorated stability with a voltage rise of more than 12 V and luminance decay of 90% after 21 h operation. On the contrary, Al/ $\text{Cs}_2\text{CO}_3$ -based device without encapsulation shows a voltage rise of only 1 V after 70 h operation in ambient condition. According to the XPS analysis on Al/ $\text{Cs}_2\text{CO}_3$  and  $\text{Cs}_2\text{CO}_3$ , the complicated hydroxylation and carbonylation reaction on evaporated  $\text{Cs}_2\text{CO}_3$  can be suppressed by inserted Al. We attribute the enhanced long-term stability of Al/ $\text{Cs}_2\text{CO}_3$  to the stable Al–O–Cs complex that is a product of evaporated  $\text{Cs}_2\text{CO}_3$  reacting with the underlying Al. The Al–O–Cs complex can also be produced by evaporating 1 nm Al between  $\text{Cs}_2\text{CO}_3$  and ETL, while the inferior electron injection at the Al/BPhen interface results in the joule heat-induced resistance at the interface. On the basis of our results, it is anticipated that the EIL Al/ $\text{Cs}_2\text{CO}_3$  will facilitate the development of highly efficient and stable inverted AMOLED.

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### Author Contributions

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### Notes

The authors declare no competing financial interest.

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